Notice of References Cited	Application/Control No. 10/685,684	Applicant(s)/Patent Under Reexamination RAMACHANDRAN ET AL.	
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	B	US-			
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	K	US-			
	L	US-			
	M	US-			

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NON-PATENT DOCUMENTS

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	U	"Cleaning Techniques for Wafer Surfaces", Semiconductor international, August 1987, pages 81-85.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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